SHIGA7 043APC PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Havashi et al.

Appl. No. : 10/565,696

Filed : January 24, 2006

For: : RESIN FOR RESIST, POSITIVE RESIST COMPOSITION, AND

METHOD OF FORMING RESIST PATTERN

Examiner : Huhn, R.

Group Art Unit 4131

AMENDMENT AND RESPONSE TO OFFICE ACTION

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

In response to the final Office Action mailed June 30, 2009, please amend the abovereferenced application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Summary of Examiner Interview begins on page 6 of this paper.

Remarks/Arguments begin on page 7 of this paper.